

WHAT IS CLAIMED IS:

1. A method of forming a carbon layer by vapor phase deposition, comprising the steps of:
adjusting a content of particles having a particle size of 0.5 μm or more in a film deposition system of the carbon layer to 1000 particles/ ft^3/min or less; and then starting a film deposition process of the carbon layer.
2. The method according to claim 1, wherein said content of the particles having the particle size of 0.5 μm or more is reduced to 500 particles/ ft^3/min .
3. The method according to claim 1, wherein said carbon layer is formed as a protective coating on a thermal head performing thermal recording.
4. The method according to claim 1, wherein a lower limit of said content of the particles having the particle size of 0.5 μm or more ranges between 50 particles/ ft^3/min and 100 particles/ ft^3/min .

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